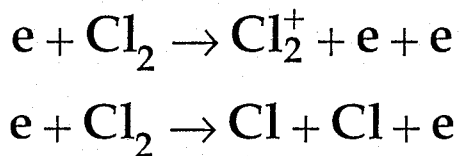
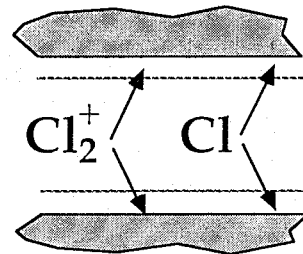


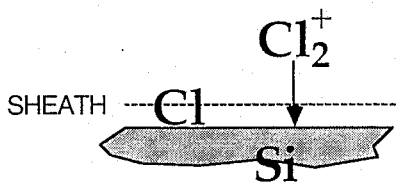
ELECTRON HEATING



RADICAL / ION GENERATION

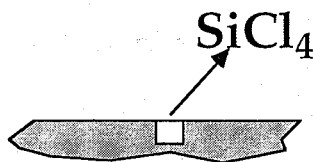


RADICAL / ION TRANSPORT TO WAFER

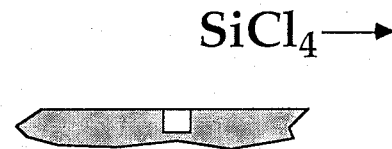


ION ACCELERATION INTO WAFER

RADICAL ADSORPTION



ETCHING



PRODUCT PUMPOUT